

Transverse Impedance Distribution Measurements Using the Response Matrix Fit at APS

Vadim Sajaev

Acknowledgements

S. Milton, L. Emery, K. Harkay, Y.-C. Chae,

H. Shang, E. Trakhtenberg

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Procedure description

- The beam sees the transverse impedance as defocusing quadrupole whose strength depends on the beam current
- At APS we use the response matrix fit method for measurement of beta functions along the ring
- We use this method to measure beta functions for different beam currents, then we calculate local phase advance changes with beam current, then we determine the transverse impedance



Response matrix fit (LOCO)

- Orbit response matrix is the change in the orbit at the BPMs as a function of the changes in the steering magnets
- The response matrix is defined by the linear lattice; therefore, it can be used to calibrate the linear optics
- Accelerators have a large number of steering magnets and precise BPMs, so the response matrix measurement generates a very large array of precise data
- The idea of the analysis is to adjust all variables upon which the response matrix depends in a computer model until the model response matrix best fits the measured response matrix

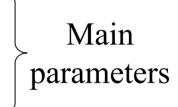


Response matrix analysis

The measured response matrix depends on the following parameters:

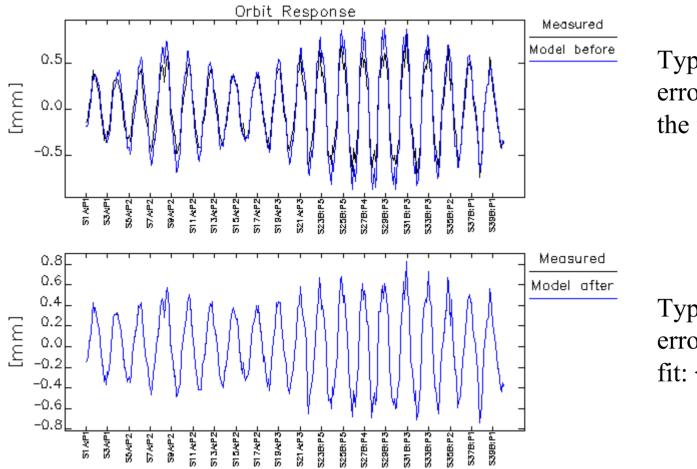
- Quadrupole gradients
- Steering magnet calibrations
- BPM gains
- Energy shift associated with steering magnet change
- BPM nonlinearity
- Steering magnet and BPM longitudinal positions

Totally, we vary about 1,400 variables to fit 32,000 elements of the response matrix





Measurements and fitting

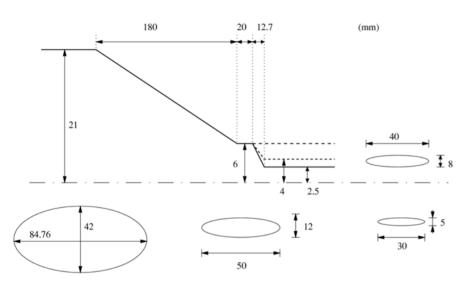


Typical rms error before the fit: 80 µm

Typical rms error after the fit: $< 2 \mu m$



Vertical impedance sources

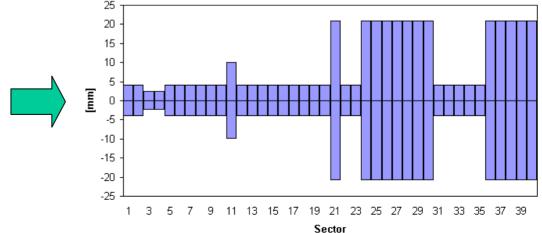




Geometry of the transition between large- and smallgap vacuum chambers

ID vacuum chamber gaps

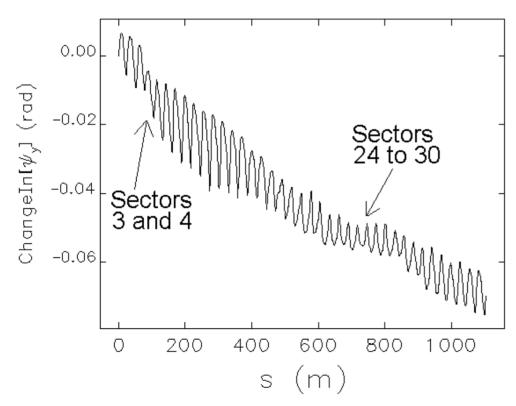
Locations of the smallgap ID vacuum chambers; each ID chamber is 5-m long aluminum extrusion





Measurements

In order to obtain the change in focusing with the beam intensity, we measure the response matrices for different beam currents, analyze them to get beta functions, and then compare the local phase advances.



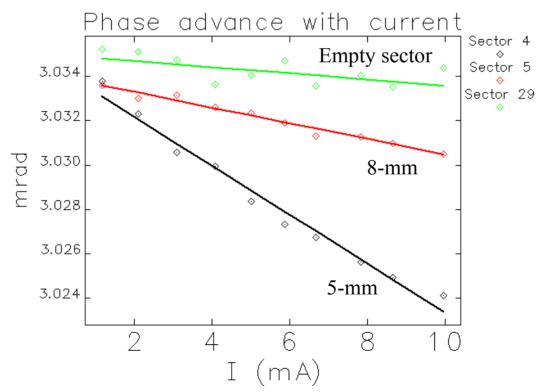
Betatron phase advance difference between 10 mA and 1 mA



Measurements

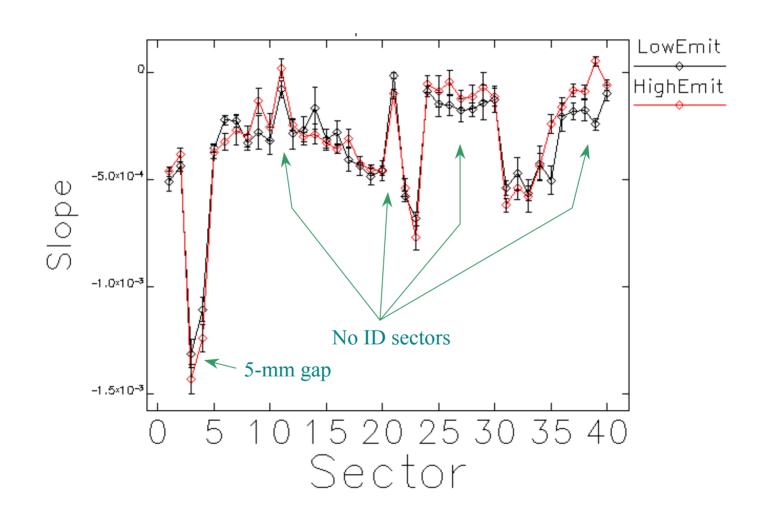
To get the local distribution of the impedance, we analyze the phase-advance changes sector by sector.

Typical phase-advance slopes for sectors with 5-mm, 8-mm, and 42-mm-gap vacuum chambers are shown below.





Vertical betatron phase slope distribution





Vertical impedance calculation

For a particular component, the effective impedance can be found from measured slopes of the phase advance:

$$Z_{eff}^{i} = \frac{E/\sigma_{s}}{R\beta_{i}} \frac{d\mu}{dI}$$

	Units	High emittance	Low emittance
$d\mu/dI_{no\ ID}$	A-1	-0.09	-0.14
$d\mu/dI_{8mm}$	A-1	-0.39	-0.40
$d\mu/dI_{5mm}$	A-1	-1.33	-1.21
$Z_{\it noID}^{\it eff}$	kΩ/m	3.5	4.1
$Z_{8mm}^{\it eff}$	kΩ/m	31	34
$Z_{\scriptscriptstyle 5mm}^{\it eff}$	kΩ/m	126	138
$Z_{\scriptscriptstyle total}^{\it eff}$	MΩ/m	1.1	1.2

Conclusion

- Vertical effective impedance distribution has been determined using the response matrix fit
- It was found that the small-gap ID vacuum chambers contribute the most to the storage ring vertical impedance
- The actual values of the vertical impedance of the chambers with different gaps were determined
- The results compare well with the impedance model (posters RPPB001-004 tomorrow) and with the earlier measurements using local orbit bumps (PAC2001 by L. Emery)